



THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 9257**  
Tetsuji TOGAWA et al. : Attorney Docket No. 2005\_0993A  
Serial No. 10/539,245 : Group Art Unit 3723  
Filed March 29, 2006 : Examiner Maurina T. Rachuba  
SUBSTRATE HOLDING MECHANISM, : **Mail Stop: AMENDMENT**  
SUBSTRATE POLISHING APPARATUS AND  
SUBSTRATE POLISHING METHOD

**PETITION FOR EXTENSION OF TIME**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Petition hereby is made for a one month extension of time to respond to the communication of September 25, 2007.

The fee of \$120.00 is

- ☒ submitted herewith.  
☐ to be charged to Deposit Account No. 23-0975. A duplicate copy of this Petition is enclosed.
- ☐ Small entity status of this application is established by a Small Entity Status Assertion which  
☐ is enclosed.  
☐ has been previously submitted.  
☐ has been previously asserted.

Respectfully submitted,

Tetsuji TOGAWA et al.

By

Nils E. Pedersen

Registration No. 33,145

Attorney for Applicant

NEP/nka  
Washington, D.C. 20006-1021  
Telephone (202) 721-8200  
Facsimile (202) 721-8250  
January 25, 2008

01 FC:1251

120.00 0P